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(54) **Apparatus for providing enhanced self-resistive specimen heating in dynamic material testing systems and an accompanying method for use therein**

Vorrichtung zur Ermöglichung der Erhitzung eines Prüflings von hoher Selbstresistenz in Systemen zur dynamischen Materialprüfung und begleitendes Verfahren zur Verwendung darin

Appareil pour la fourniture d'un chauffage amélioré à résistance propre d'échantillons dans des systèmes dynamiques d'essai de matériaux et procédé correspondant

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